



TJK/203

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of :) APPARATUS AND METHOD
) FOR THIN FILM DEPOSITION
 Chan-Soo PARK et al.)
) Examiner: R. Zervigon
 Application No. 10/039,357)
) Art Unit: 1763
 Application Filing Date: November 7, 2001)
)

RESPONSE TO OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Mail Stop: Fee Amendment

Dear Sir:

This paper is in response to the Office Action mailed December 8, 2003.

IN THE CLAIMS:

Please amend the claims as follows:

1. (Currently Amended) An apparatus for forming a thin film, comprising:
 - a reaction chamber having a top portion, a sidewall portion and a bottom portion;
 - a gas injector penetrating the top portion and letting a source element pass therethrough;
 - a distributor connected to the gas injector by screw threads, the distributor comprising a first portion having a cylindrical shape, a second portion shaped like a truncated cone, and a plurality of injection holes, wherein a plurality of injection holes are formed in the distributor and the source element is injected through the plurality of injection holes; and